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CLAIMS

What is claimed is:

1	1.	A system for lapping a head, comprising:
2	(a)	a wafer including at least one head each having an electrical lapping guide (ELG),
3		a plurality of wafer contacts in electrical communication with the ELG, and a
4		closure formed thereon defining a slot in which the wafer contacts are positioned;
5	(b)	a lapping cable coupled to a testing device, the lapping cable including a plurality
6		of lapping cable contacts; and
7	(c)	an adapter including a plurality of adapter contacts in electrical communication
8		with the lapping cable contacts;
9	(d)	wherein the adapter contacts are removably positionable in electrical
10		communication with the wafer contacts during a lapping process.
1	2.	The system as recited in claim 1, wherein the adapter is constructed from a
2		polyimide material.
1	3.	The system as recited in claim 1, wherein adapter includes a pair of holes formed

alignment pins.

therein for coupling with a pair of holes formed in the lapping cable via a pair of

- 1 4. The system as recited in claim 1, wherein the adapter includes at least one guide
- 2 for being removably positioned in a slot defined by closures of adjacent heads
- 3 formed on the wafer.
- 1 5. The system as recited in claim 1, wherein the adapter contacts are slidably
- 2 coupled to the adapter.
- 1 6. The system as recited in claim 1, wherein the adapter contacts each include a first
- 2 portion in electrical communication with one of the lapping cable contacts and a
- 3 second portion in electrical communication with one of the wafer contacts.
- 1 7. The system as recited in claim 6, wherein the first portion of each adapter contact
- 2 is larger than the second portion of each adapter contact.
- 1 8. The system as recited in claim 7, wherein the first portion of each adapter contact
- 2 has a diameter larger than that of the second portion of each adapter contact.
- 1 9. The system as recited in claim 6, wherein the adapter includes a recess for
- 2 preventing contact with the wafer during the lapping process.
- 1 10. An system for lapping a head, comprising:

2	(a)	a wafer including at least one head each having an electrical lapping guide (ELG)
3		a plurality of wafer contacts in electrical communication with the ELG, and a
4		closure formed thereon defining a slot in which the wafer contacts are positioned;
5		and
6	(b)	a lapping cable coupled to a testing device, the lapping cable including a plurality
7		of lapping cable contacts extending outwardly therefrom;
8	(c)	wherein the lapping cable contacts are removably positionable in electrical
9		communication with the wafer contacts during a lapping process.
1	11.	The system as recited in claim 10, wherein the lapping cable includes at least one
2		guide for being removably positioned in a slot defined by closures of adjacent
3		heads formed on the wafer.
1	12.	The system as recited in claim 10, wherein the lapping cable contacts extend in a
2		direction perpendicular with respect to the lapping cable.
1	13.	The system as recited in claim 10, wherein the lapping cable includes a recess for
2		preventing contact with the wafer during the lapping process.
1	14.	An apparatus for use with a wafer including at least one head each having an
2		electrical lapping guide (ELG), a plurality of wafer contacts in electrical
3		communication with the ELG, and a closure formed thereon defining a slot in
4		which the wafer contacts are positioned, and a lapping cable coupled to a testing

device, the lapping cable including a plurality of lapping cable contacts; the
apparatus comprising: an adapter including a plurality of adapter contacts in
electrical communication with the lapping cable contacts, wherein the adapter
contacts are removably positionable in electrical communication with the wafer
contacts during a lapping process.

- An apparatus for use with a wafer including at least one head each having an 15. 1 electrical lapping guide (ELG), a plurality of wafer contacts in electrical 2 communication with the ELG, and a closure formed thereon defining a slot in 3 which the wafer contacts are positioned, the apparatus comprising: 4 a lapping cable coupled to a testing device, the lapping cable including a plurality 5 (a) of lapping cable contacts extending outwardly therefrom in direction 6 perpendicular with respect to the lapping cable; 7 wherein the lapping cable contacts are removably positionable in electrical 8 (b) communication with the wafer contacts during a lapping process. 9
 - An adapter including a plurality of adapter contacts in electrical communication with a plurality of lapping cable contacts of the lapping cable, wherein the adapter contacts are removably positionable in electrical communication with a plurality of wafer contacts of a wafer during a lapping process.
- 1 17. A lapping cable coupled to a testing device and including a plurality of lapping cable contacts extending outwardly therefrom in a direction perpendicular with

- respect to the lapping cable, wherein the lapping cable contacts are removably
 positionable in electrical communication with a plurality of wafer contacts of a
 wafer during a lapping process.
- An adapter including a plurality of adapter contacts in electrical communication
 with a plurality of lapping cable contacts of the lapping cable, the adapter further
 including at least one guide for being removably positioned in a slot defined by
 closures of adjacent heads formed on the wafer, and a recess for preventing
 contact with the wafer during the lapping process, wherein the adapter contacts
 are removably positionable in electrical communication with a plurality of wafer
 contacts of the wafer during a lapping process.
- 1 19. A method for testing during a lapping process, comprising:
- (a) providing an adapter including a plurality of adapter contacts in electrical
 communication with a plurality of lapping cable contacts of the lapping cable;
- 4 (b) removably positioning the adapter contacts of the adapter in electrical
 5 communication with a plurality of wafer contacts of a wafer;
- 6 (c) lapping a surface of the wafer; and
- 7 (d) measuring a head of the wafer during the lapping process.